ScanMax®

Specifications



New!

Optional:

With increased accuracy in preferred measuring range

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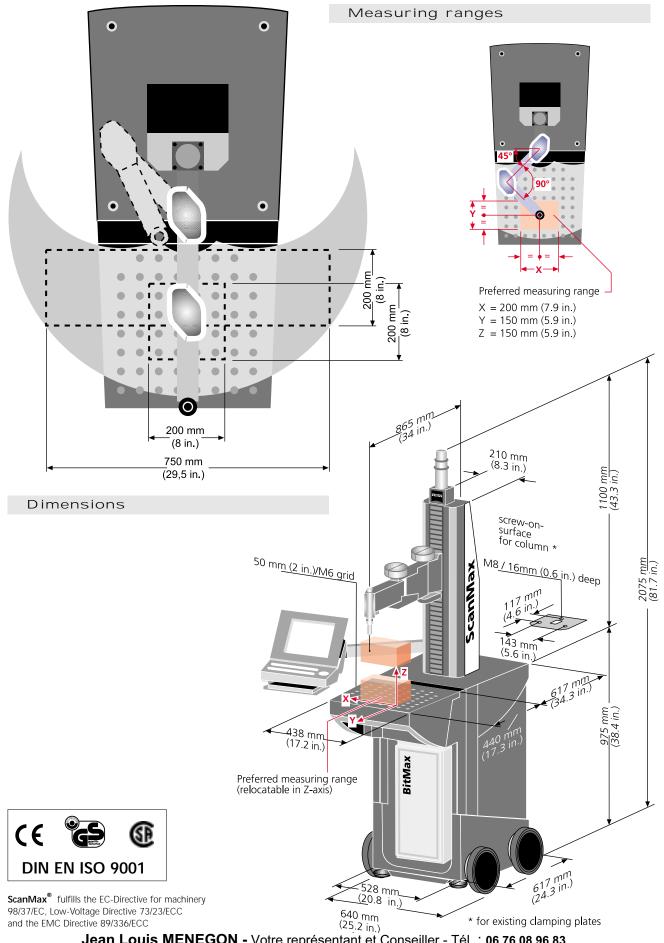
Worker self inspection in the shopfloor, in scanning mode.

- reliable
- fast
- simple to use



We make it visible.

ScanMax[®]. For Shopfloor Use.



ScanMax®. Technical Data and Performance.

General		S canMax®			
Design		Articulating arm CN	IM		
Probe system		Zeiss measuring pro			
Drives		High dynamic servo	drive.		
			itoring and thrust force lin		
Control		Dual PC control with ScanWarePRO evaluation software and Windows 2000 operating system Manual scanning of workpiece features and contours, motorized in the Z-axis			
Operation					
Special features		Absolute precision due to design quality and patented correction techniques. Collision protection in vertical direction.			
		9	mode with a data capture	'	
		Light-weight articulated arms made of carbon fiber – for manual scanning. Ulta-precise, integrated roller bearings for outstanding running accuracies. Workpiece chucking on rotary tilting table with automatic ledge measurement for shifting and			
		Polymer cocrete base with excellent inhere stability (optional). Optionally equipped with wheels for easy transport.			
Massuring range Dim	amaiana Maia	h.+			
Measuring range, Dim	emsions, weigi	nt			
Travel paths	maximal in mm (in.)	width	deepth	height	
		850 (33.5)	400 (15.7)	450 (17.7)	
Measuring ranges	unidate to occur (C.)	See Drawing on left			
Dimensions Basic machine	width in mm (in.)	deepth in mm (in.)		1100 (42.2)	
Basic machine Base	(without wheels)	210 (8.3) 528 (20.8)	865 (34) 1057 (41.6)	1100 (43.3) 975 (38.4)	
Dasc	(with wheels)	640 (25.2)	1057 (41.6)	980 (38.6)	
Complete machine	(without wheels)	528 (20.8)	1057 (41.6)	2075 (81.7)	(without support arm)
22	(with wheels)	640 (25.2)	1057 (41.6)	2080 (81.9)	(without support arm)
Clamping plate	, , , , , , , , , ,	438 (17.2)	440 (17.3)	50 (2)	11111111111
Electronics unit (IP 54)		285 (11.2)	485 (19.1)	620 (24.4)	
Space requirement Floo	or area incl. clearance	1200 mm x 1500 m	m (47.2 x 59.1 in.)		
Floor area	incl. clearance & cart	1200 mm x 2000 m	m (47.2 x 78.4 in.)		
Weight	in kg (lb)	Machine: 60 (132)		ctronics unit: 25 (55)
Max. workpiece weight	in kg (lb)	50 (110) (on Zeiss b	ase)		
Performance Data		Standard		Optional	
Length (size) measuring error 1)		Total measuring ra	ngo	Preferred meas	uring range
MPF acc EN ISO 10360-2	for F in IIm (in)	5 0 ± 1/50 (0 000 10	27 ± 1/50 000\ 3)	2 9 ± 1/50 (0 00)	
	for E in µm (in.)	5.0 + L/50 (0.000 19 4.5 + L/60 (0.000 15	97 + L/50,000) ³⁾ 77 + L/60.000) (XY-plane) (2.9 + L/50 (0.000 2) 2.4 + L/60 (0.000	
acc. VDI/VDE 2617	u ₂ in µm (in.)	4.5 + L/60 (0.000 17	77 + L/60,000) (XY-plane) ²	²⁾ 2.4 + L/60 (0.000	0 094 + L/60,000) (XY-plane) 0 114 + L/50,000) (2)
acc. VDI/VDE 2617 (Length measuring uncertainty)	, , ,	5.0 + L/50 (0.000 19 4.5 + L/60 (0.000 19 5.0 + L/50 (0.000 19	77 + L/60,000) (XY-plane) ²	²⁾ 2.4 + L/60 (0.00)	0 094 + L/60,000) (XY-plane)
acc. VDI/VDE 2617 (Length measuring uncertainty) Probing error	u ₂ in μm (in.) u ₃ in μm (in.)	4.5 + L/60 (0.000 17 5.0 + L/50 (0.000 19	77 + L/60,000) (XY-plane) ²	²⁾ 2.4 + L/60 (0.00)	0 094 + L/60,000) (XY-plane)
acc. VDI/VDE 2617 (Length measuring uncertainty) Probing error following to MPE	u ₂ in µm (in.)	4.5 + L/60 (0.000 17 5.0 + L/50 (0.000 19	77 + L/60,000) (XY-plane) ²	²⁾ 2.4 + L/60 (0.00)	0 094 + L/60,000) (XY-plane)
acc. VDI/VDE 2617 (Length measuring uncertainty) Probing error following to MPE acc. EN ISO 10360-2	u_2 in μ m (in.) u_3 in μ m (in.) for P in μ m (in.) 2)	4.5 + L/60 (0.000 1.5.0 + L/50 (0.000 16) 5.5 (0.000 216)	77 + L/60,000) (XY-plane) ²	²⁾ 2.4 + L/60 (0.00)	0 094 + L/60,000) (XY-plane)
acc. VDI/VDE 2617 (Length measuring uncertainty) Probing error following to MPE acc. EN ISO 10360-2 acc. VDI/VDE 2617 3)	$\begin{array}{c} u_2 \text{in } \mu\text{m (in.)} \\ u_3 \text{in } \mu\text{m (in.)} \end{array}$ $\begin{array}{c} \text{for P} \text{in } \mu\text{m (in.)} ^2) \\ V_2 \text{in } \mu\text{m (in.)} ^2) \end{array}$	4.5 + L/60 (0.000 17 5.0 + L/50 (0.000 19 5.5 (0.000 216) 3.0 (0.000 118)	77 + L/60,000) (XY-plane) ²	²⁾ 2.4 + L/60 (0.00)	0 094 + L/60,000) (XY-plane)
acc. VDI/VDE 2617 (Length measuring uncertainty) Probing error following to MPE acc. EN ISO 10360-2 acc. VDI/VDE 2617 ³⁾ Form measurement error RON_t /	$\begin{array}{c} u_2 \text{in } \mu\text{m (in.)} \\ u_3 \text{in } \mu\text{m (in.)} \end{array}$ $\begin{array}{c} \text{for P} \text{in } \mu\text{m (in.)} ^2) \\ V_2 \text{in } \mu\text{m (in.)} ^2) \end{array}$	4.5 + L/60 (0.000 1.5.0 + L/50 (0.000 16) 5.5 (0.000 216)	77 + L/60,000) (XY-plane) ²	²⁾ 2.4 + L/60 (0.00)	0 094 + L/60,000) (XY-plane)
acc. VDI/VDE 2617 (Length measuring uncertainty) Probing error following to MPE acc. EN ISO 10360-2 acc. VDI/VDE 2617 3) Form measurement error RON _t / following to MPE	$\begin{array}{c} u_2 \;\; \text{in } \mu \text{m (in.)} \\ u_3 \;\; \text{in } \mu \text{m (in.)} \\ \\ \textbf{for P} \qquad \text{in } \mu \text{m (in.)} \; ^2) \\ V_2 \;\; \text{in } \mu \text{m (in.)} \; ^2) \\ \textbf{MZCI} \;\; \text{in } \mu \text{m (in.)} \; ^2) \;\; ^4) \end{array}$	4.5 + L/60 (0.000 17 5.0 + L/50 (0.000 19 5.5 (0.000 216) 3.0 (0.000 118)	77 + L/60,000) (XY-plane) ²	²⁾ 2.4 + L/60 (0.00)	0 094 + L/60,000) (XY-plane)
acc. VDI/VDE 2617 (Length measuring uncertainty) Probing error following to MPE acc. EN ISO 10360-2 acc. VDI/VDE 2617 3) Form measurement error RON _t / following to MPE acc.DIN EN ISO12181 (VDI/VDE 261	u_2 in μ m (in.) u_3 in μ m (in.) for P in μ m (in.) 2) V_2 in μ m (in.) 2) MZCI in μ m (in.) 2) 4) 17 part 2.2)	4.5 + L/60 (0.000 15 5.0 + L/50 (0.000 16 5.5 (0.000 216) 3.0 (0.000 118) 6.0 (0.000 236)	77 + L/60,000) (XY-plane) ³ 97 + L/50,000) ³)	2) 2.4 + L/60 (0.000 2.9 + L/50 (0.000	0 094 + L/60,000) (XY-plane) 0 114 + L/50,000) ²)
acc. VDI/VDE 2617 (Length measuring uncertainty) Probing error following to MPE acc. EN ISO 10360-2 acc. VDI/VDE 2617 3) Form measurement error RON _t / following to MPE acc.DIN EN ISO12181 (VDI/VDE 261	u_2 in μ m (in.) u_3 in μ m (in.) for P in μ m (in.) v_2 in μ m (in.) v_3 in v_4 in $v_$	4.5 + L/60 (0.000 13 5.0 + L/50 (0.000 14 5.5 (0.000 216) 3.0 (0.000 118) 6.0 (0.000 236) Zerodur scale; reflec	77 + L/60,000) (XY-plane) ³ 97 + L/50,000) ³ ted light system/photoelec	2) 2.4 + L/60 (0.000 2.9 + L/50 (0.000 tric; resolution 0.5 μ	0 094 + L/60,000) (XY-plane) 0 114 + L/50,000) ²) m
acc. VDI/VDE 2617 (Length measuring uncertainty) Probing error following to MPE acc. EN ISO 10360-2 acc. VDI/VDE 2617 3) Form measurement error RON _t / following to MPE acc.DIN EN ISO12181 (VDI/VDE 261) Length measuring systems	u_2 in μ m (in.) u_3 in μ m (in.) for P in μ m (in.) 2) V_2 in μ m (in.) 2) MZCI in μ m (in.) 2) 4) 17 part 2.2)	4.5 + L/60 (0.000 13 5.0 + L/50 (0.000 14 5.5 (0.000 216) 3.0 (0.000 118) 6.0 (0.000 236) Zerodur scale; reflecting Glass graduated circles	ted light system/photoelec with dual scanning; tran	2) 2.4 + L/60 (0.000 2.9 + L/50 (0.000 tric; resolution 0.5 μ smitted light system	0 094 + L/60,000) (XY-plane) 0 114 + L/50,000) ²) m /photoelectric; resolution 0.4
acc. VDI/VDE 2617 (Length measuring uncertainty) Probing error following to MPE acc. EN ISO 10360-2 acc. VDI/VDE 2617 3) Form measurement error RON _t / following to MPE acc.DIN EN ISO12181 (VDI/VDE 261) Length measuring systems	u_2 in μ m (in.) u_3 in μ m (in.) for P in μ m (in.) v_2 in μ m (in.) v_3 in v_4 in $v_$	4.5 + L/60 (0.000 17 5.0 + L/50 (0.000 19 5.5 (0.000 216) 3.0 (0.000 118) 6.0 (0.000 236) Zerodur scale; reflecting Glass graduated circular scales and circular scales are supported to the circular scales and circular scales are supported to the circular scales are scales are supported to the circular scales are s	ted light system/photoelec with dual scanning; transem on carrier frequency b.	2) 2.4 + L/60 (0.000 2.9 + L/50 (0.000 tric; resolution 0.5 μ smitted light system	0 094 + L/60,000) (XY-plane) 0 114 + L/50,000) ²) m /photoelectric; resolution 0.4
acc. VDI/VDE 2617 (Length measuring uncertainty) Probing error following to MPE acc. EN ISO 10360-2 acc. VDI/VDE 2617 ³) Form measurement error RON _t / following to MPE acc.DIN EN ISO12181 (VDI/VDE 261 Length measuring systems	$\begin{array}{c} u_2 \text{ in } \mu\text{m (in.)} \\ u_3 \text{ in } \mu\text{m (in.)} \\ \\ \textbf{for P} \text{ in } \mu\text{m (in.)} & 2) \\ V_2 \text{ in } \mu\text{m (in.)} & 2) \\ \textbf{MZCI in } \mu\text{m (in.)} & 2) & 4) \\ 17 \text{ part } & 2.2) \\ \hline & Z-\text{axis} \\ \text{Rotating axes} \\ \end{array}$	4.5 + L/60 (0.000 17 5.0 + L/50 (0.000 19 5.5 (0.000 216) 3.0 (0.000 118) 6.0 (0.000 236) Zerodur scale; reflect Glass graduated circles and the circles of the circl	ted light system/photoelec with dual scanning; transem on carrier frequency b.	2) 2.4 + L/60 (0.000 2.9 + L/50 (0.000 tric; resolution 0.5 μ smitted light system	0 094 + L/60,000) (XY-plane) 0 114 + L/50,000) ²) m /photoelectric; resolution 0.4
acc. VDI/VDE 2617 (Length measuring uncertainty) Probing error following to MPE acc. EN ISO 10360-2 acc. VDI/VDE 2617 ³⁾ Form measurement error RON _t / following to MPE acc.DIN EN ISO12181 (VDI/VDE 261 Length measuring systems Probing system Measuring forces during data captu	$\begin{array}{c} u_2 \text{ in } \mu\text{m (in.)} \\ u_3 \text{ in } \mu\text{m (in.)} \\ \\ \textbf{for P} \text{ in } \mu\text{m (in.)} & 2) \\ V_2 \text{ in } \mu\text{m (in.)} & 2) \\ \textbf{MZCI in } \mu\text{m (in.)} & 2) & 4) \\ 17 \text{ part } & 2.2) \\ \hline & Z-\text{axis} \\ \text{Rotating axes} \\ \end{array}$	4.5 + L/60 (0.000 13 5.0 + L/50 (0.000 14 5.5 (0.000 216) 3.0 (0.000 118) 6.0 (0.000 236) Zerodur scale; reflec Glass graduated circ Inductive sensor syst even with higher spr approx. 0.5 - 2 N	ted light system/photoelec le with dual scanning; transeeds	2) 2.4 + L/60 (0.000 2.9 + L/50 (0.000 tric; resolution 0.5 μ asmitted light system asis for determining	0 094 + L/60,000) (XY-plane) 0 114 + L/50,000) ²) m /photoelectric; resolution 0.4
acc. VDI/VDE 2617 (Length measuring uncertainty) Probing error following to MPE acc. EN ISO 10360-2 acc. VDI/VDE 2617 ³⁾ Form measurement error RON _t / following to MPE acc.DIN EN ISO12181 (VDI/VDE 261 Length measuring systems Probing system Measuring forces during data captus Stylus weight	$\begin{array}{c} u_2 \text{ in } \mu\text{m (in.)} \\ u_3 \text{ in } \mu\text{m (in.)} \\ \\ \textbf{for P} \text{ in } \mu\text{m (in.)} & 2) \\ V_2 \text{ in } \mu\text{m (in.)} & 2) \\ \textbf{MZCI in } \mu\text{m (in.)} & 2) & 4) \\ 17 \text{ part } & 2.2) \\ \hline & Z-\text{axis} \\ \text{Rotating axes} \\ \end{array}$	4.5 + L/60 (0.000 13 5.0 + L/50 (0.000 14 5.5 (0.000 216) 3.0 (0.000 118) 6.0 (0.000 236) Zerodur scale; reflecting Glass graduated circular sensor system with higher sprapprox. 0.5 - 2 Nth 135 g (4.8 oz.) basic	ted light system/photoelec le with dual scanning; transem on carrier frequency beeds c setting to higher values p	2) 2.4 + L/60 (0.000 2.9 + L/50 (0.000 tric; resolution 0.5 μ asmitted light system asis for determining	0 094 + L/60,000) (XY-plane) 0 114 + L/50,000) ²) m /photoelectric; resolution 0.4
acc. VDI/VDE 2617 (Length measuring uncertainty) Probing error following to MPE acc. EN ISO 10360-2 acc. VDI/VDE 2617 ³⁾ Form measurement error RON _t / following to MPE acc.DIN EN ISO12181 (VDI/VDE 261 Length measuring systems Probing system Measuring forces during data captus Stylus weight Max. stylus length	$\begin{array}{c} u_2 \text{ in } \mu\text{m (in.)} \\ u_3 \text{ in } \mu\text{m (in.)} \\ \\ \textbf{for P} \text{ in } \mu\text{m (in.)} & 2) \\ V_2 \text{ in } \mu\text{m (in.)} & 2) \\ \textbf{MZCI in } \mu\text{m (in.)} & 2) & 4) \\ 17 \text{ part } & 2.2) \\ \hline & Z-\text{axis} \\ \text{Rotating axes} \\ \end{array}$	4.5 + L/60 (0.000 13 5.0 + L/50 (0.000 16 5.5 (0.000 216) 3.0 (0.000 118) 6.0 (0.000 236) Zerodur scale; reflecting Glass graduated circular inductive sensor systems with higher speapprox. 0.5 - 2 Nth 135 g (4.8 oz.) basic approx. 300 mm (11)	ted light system/photoelec le with dual scanning; transem on carrier frequency beeds c setting to higher values p	2) 2.4 + L/60 (0.000 2.9 + L/50 (0.000 tric; resolution 0.5 μ asmitted light system asis for determining	0 094 + L/60,000) (XY-plane) 0 114 + L/50,000) ²) m /photoelectric; resolution 0.4
acc. VDI/VDE 2617 (Length measuring uncertainty) Probing error following to MPE acc. EN ISO 10360-2 acc. VDI/VDE 2617 ³⁾ Form measurement error RON _t / following to MPE acc.DIN EN ISO12181 (VDI/VDE 261 Length measuring systems Probing system Measuring forces during data captus Stylus weight Max. stylus length Smallest stylus tip diameter	$\begin{array}{c} u_2 \text{ in } \mu\text{m (in.)} \\ u_3 \text{ in } \mu\text{m (in.)} \\ \\ \textbf{for P} \text{ in } \mu\text{m (in.)} & 2) \\ V_2 \text{ in } \mu\text{m (in.)} & 2) \\ \textbf{MZCI in } \mu\text{m (in.)} & 2) & 4) \\ 17 \text{ part } & 2.2) \\ \hline & Z-\text{axis} \\ \text{Rotating axes} \\ \end{array}$	4.5 + L/60 (0.000 13 5.0 + L/50 (0.000 14 5.5 (0.000 216) 3.0 (0.000 118) 6.0 (0.000 236) Zerodur scale; reflecting Glass graduated circum Series Glass	ted light system/photoelec le with dual scanning; transem on carrier frequency baseds es setting to higher values p 1.8 in.)	2) 2.4 + L/60 (0.000 2.9 + L/50 (0.000 tric; resolution 0.5 μ asmitted light system asis for determining	0 094 + L/60,000) (XY-plane) 0 114 + L/50,000) ²) m /photoelectric; resolution 0.4
acc. VDI/VDE 2617 (Length measuring uncertainty) Probing error following to MPE acc. EN ISO 10360-2 acc. VDI/VDE 2617 ³⁾ Form measurement error RON _t / following to MPE acc.DIN EN ISO12181 (VDI/VDE 261 Length measuring systems Probing system Measuring forces during data captus Stylus weight Max. stylus length Smallest stylus tip diameter	$\begin{array}{c} u_2 \text{ in } \mu\text{m (in.)} \\ u_3 \text{ in } \mu\text{m (in.)} \\ \\ \textbf{for P} \text{ in } \mu\text{m (in.)} & 2) \\ V_2 \text{ in } \mu\text{m (in.)} & 2) \\ \textbf{MZCI in } \mu\text{m (in.)} & 2) & 4) \\ 17 \text{ part } & 2.2) \\ \hline & Z-\text{axis} \\ \text{Rotating axes} \\ \end{array}$	4.5 + L/60 (0.000 17 5.0 + L/50 (0.000 18 5.5 (0.000 216) 3.0 (0.000 118) 6.0 (0.000 236) Zerodur scale; reflecting Glass graduated circles are with higher spectors of the second	ted light system/photoelectle with dual scanning; transem on carrier frequency beeds setting to higher values pt. 8 in.)	2) 2.4 + L/60 (0.000 2.9 + L/50 (0.000 tric; resolution 0.5 μ asmitted light system asis for determining	0 094 + L/60,000) (XY-plane) 0 114 + L/50,000) ²) m /photoelectric; resolution 0.4
acc. VDI/VDE 2617 (Length measuring uncertainty) Probing error following to MPE acc. EN ISO 10360-2 acc. VDI/VDE 2617 ³) Form measurement error RON _t / following to MPE acc.DIN EN ISO12181 (VDI/VDE 261 Length measuring systems Probing system Measuring forces during data captus Stylus weight Max. stylus length Smallest stylus tip diameter Stylus changing system	$\begin{array}{c} u_2 \text{ in } \mu\text{m (in.)} \\ u_3 \text{ in } \mu\text{m (in.)} \\ \\ \textbf{for P} \text{ in } \mu\text{m (in.)} & 2) \\ V_2 \text{ in } \mu\text{m (in.)} & 2) \\ \textbf{MZCI in } \mu\text{m (in.)} & 2) & 4) \\ 17 \text{ part } & 2.2) \\ \hline & Z-\text{axis} \\ \text{Rotating axes} \\ \end{array}$	4.5 + L/60 (0.000 17 5.0 + L/50 (0.000 18 5.5 (0.000 216) 3.0 (0.000 118) 6.0 (0.000 236) Zerodur scale; reflecting Glass graduated circles are with higher spectors of the second	ted light system/photoelec le with dual scanning; transem on carrier frequency baseds es setting to higher values p 1.8 in.)	2) 2.4 + L/60 (0.000 2.9 + L/50 (0.000 tric; resolution 0.5 μ asmitted light system asis for determining	0 094 + L/60,000) (XY-plane) 0 114 + L/50,000) ²) m /photoelectric; resolution 0.4
acc. VDI/VDE 2617 (Length measuring uncertainty) Probing error following to MPE acc. EN ISO 10360-2 acc. VDI/VDE 2617 ³) Form measurement error RON _t / following to MPE acc.DIN EN ISO12181 (VDI/VDE 261 Length measuring systems Probing system Measuring forces during data captus Stylus weight Max. stylus length Smallest stylus tip diameter Stylus changing system S upply Data	$\begin{array}{c} u_2 \text{ in } \mu\text{m (in.)} \\ u_3 \text{ in } \mu\text{m (in.)} \\ \\ \textbf{for P} \text{ in } \mu\text{m (in.)} & 2) \\ V_2 \text{ in } \mu\text{m (in.)} & 2) \\ \textbf{MZCI in } \mu\text{m (in.)} & 2) & 4) \\ 17 \text{ part } & 2.2) \\ \hline & Z-\text{axis} \\ \text{Rotating axes} \\ \end{array}$	4.5 + L/60 (0.000 13 5.0 + L/50 (0.000 14 5.5 (0.000 216) 3.0 (0.000 118) 6.0 (0.000 236) Zerodur scale; reflect Glass graduated circo Inductive sensor systeven with higher spapprox. 0.5 - 2 N 135 g (4.8 oz.) basic approx. 300 mm (11 1.5 mm (0.06 in.) Manual, patented st Absolute coding of 6	ted light system/photoelec le with dual scanning; transem on carrier frequency beeds as setting to higher values particles in.)	2) 2.4 + L/60 (0.000 2.9 + L/50 (0.000 tric; resolution 0.5 μ asmitted light system asis for determining	0 094 + L/60,000) (XY-plane) 0 114 + L/50,000) ²) m /photoelectric; resolution 0.4
acc. VDI/VDE 2617 (Length measuring uncertainty) Probing error following to MPE acc. EN ISO 10360-2 acc. VDI/VDE 2617 ³) Form measurement error RON _t / following to MPE acc.DIN EN ISO12181 (VDI/VDE 261 Length measuring systems Probing system Measuring forces during data captus Stylus weight Max. stylus length Smallest stylus tip diameter Stylus changing system S upply Data Power requirements	u ₂ in μm (in.) u ₃ in μm (in.) for P in μm (in.) 2) V ₂ in μm (in.) 2) MZCI in μm (in.) 2) 4) 17 part 2.2) Z-axis Rotating axes	4.5 + L/60 (0.000 13 5.0 + L/50 (0.000 14 5.5 (0.000 216) 3.0 (0.000 118) 6.0 (0.000 236) Zerodur scale; reflect Glass graduated circ Inductive sensor systeven with higher spaprox. 0.5 - 2 N 135 g (4.8 oz.) basic approx. 300 mm (11 1.5 mm (0.06 in.) Manual, patented st Absolute coding of 6	ted light system/photoelec le with dual scanning; transem on carrier frequency beeds as setting to higher values particles in.) ylus change. each stylus via a CD chip	2) 2.4 + L/60 (0.000 2.9 + L/50 (0.000 tric; resolution 0.5 μ asmitted light system asis for determining	0 094 + L/60,000) (XY-plane) 0 114 + L/50,000) ²) m /photoelectric; resolution 0.4
acc. VDI/VDE 2617 (Length measuring uncertainty) Probing error following to MPE acc. EN ISO 10360-2 acc. VDI/VDE 2617 ³) Form measurement error RON _t / following to MPE acc.DIN EN ISO12181 (VDI/VDE 261 Length measuring systems Probing system Measuring forces during data captus Stylus weight Max. stylus length Smallest stylus tip diameter Stylus changing system S upply Data Power requirements Optic	u ₂ in µm (in.) u ₃ in µm (in.) for P in µm (in.) 2) V ₂ in µm (in.) 2) MZCI in µm (in.) 2) 4) 17 part 2.2) Z-axis Rotating axes ure	4.5 + L/60 (0.000 13 5.0 + L/50 (0.000 13 5.5 (0.000 216) 3.0 (0.000 118) 6.0 (0.000 236) Zerodur scale; reflecting from the sensor system of the senso	ted light system/photoelec le with dual scanning; transem on carrier frequency beeds as setting to higher values particles in.)	2) 2.4 + L/60 (0.000 2.9 + L/50 (0.000 tric; resolution 0.5 μ asmitted light system asis for determining	0 094 + L/60,000) (XY-plane) 0 114 + L/50,000) ²) m /photoelectric; resolution 0.4
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²⁾ Measured with standard probe stylus diameter 8 mm (0,3 in.), probe length 53 mm (2.1 in.), probe extension 100 mm (3.9 in.)

3) Measured with standard probe stylus diameter 8 mm (0,3 in.), probe length 53 mm (2.1 in.), probe extension 163 mm (6.4 in.)



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